

CG2027 Transistor-Level Digital Circuits

***Handout #5:
Memory***

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Lecture Overview

In this lecture, you will learn about

- Memory
 - SRAM
 - DRAM
 - Flash
 - Future memories

Overview

- Memory classification
- Memory architecture
 - Core / Peripheral
- Memory in the market
 - Flash memory (NAND / NOR)
 - SRAM
 - DRAM (EDO, DDR, DDR2, DDR3 / ~ GDDR5)
 - Future memory

MOS Memory Classification

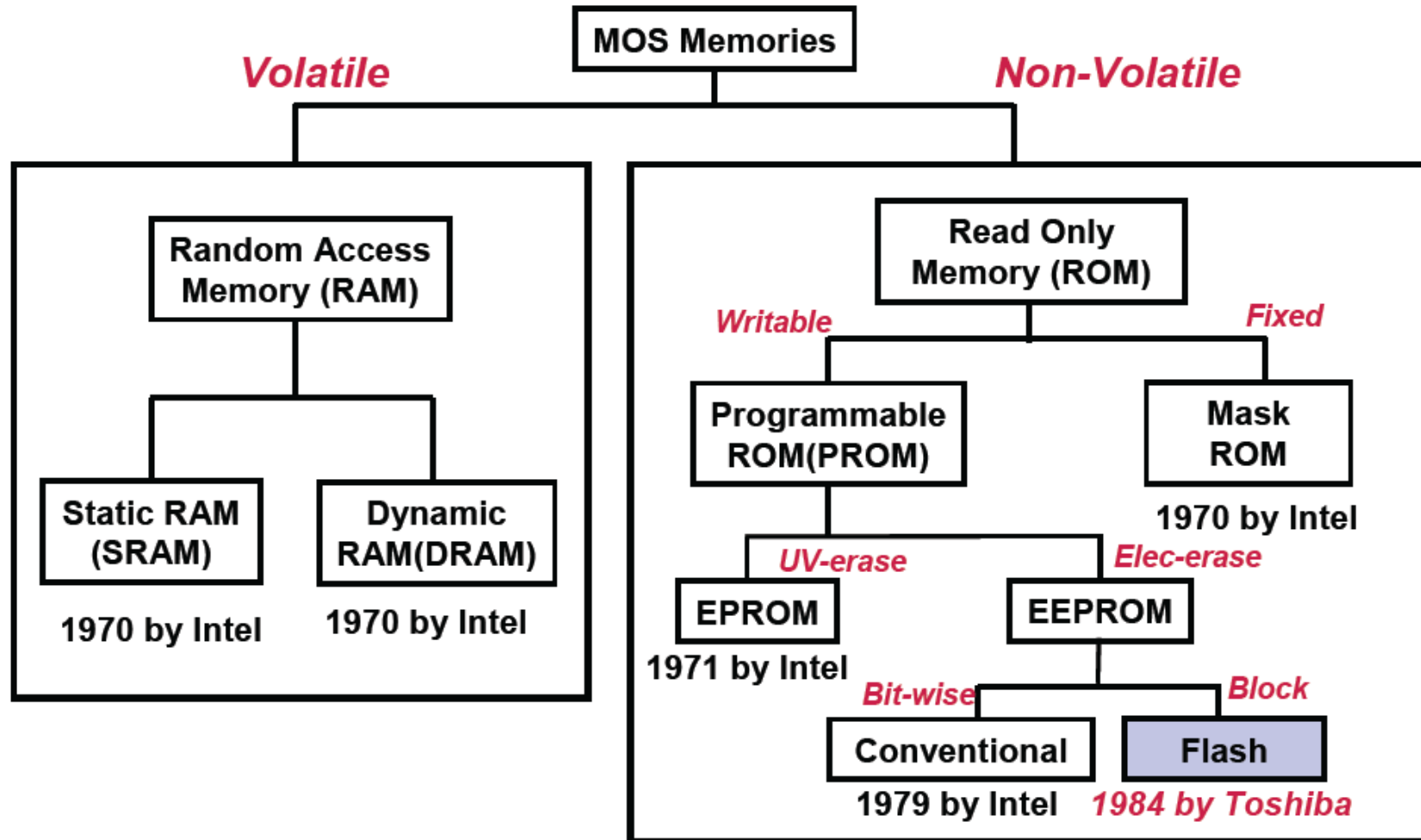


Figure-1 4Q17 Global Branded DRAM Revenue Ranking

Unit: Million USD

Ranking	Company	Revenue			Market Share	
		4Q17	3Q17	QoQ	4Q17	3Q17
1	Samsung	10,066	8,790	14.5%	46.0%	45.8%
2	SK Hynix	6,291	5,514	14.1%	28.7%	28.7%
3	Micron Group	4,562	4,023	13.4%	20.8%	21.0%
4	Nanya	558	439	26.9%	2.5%	2.3%
5	Winbond	173	177	-2.2%	0.8%	0.9%
6	Powerchip	104	103	0.6%	0.5%	0.5%
	Others	144	135	7.0%	0.7%	0.7%
	Total	21,898	19,181	14.2%	100.0%	100.0%

Note 1: 3Q17 USD\$1: KRW\$1,131; US\$1: TWD\$30.25

Note 2: 3Q17 USD\$1: KRW\$1,105; US\$1: TWD\$30.1

Source: DRAMeXchange, Feb., 2018

Table: 4Q17 Revenue Ranking of Branded NAND Flash Makers

Company	Revenue (USD\$M)		Market Share(%)	
	4Q17	QoQ (%)	4Q17	3Q17
Samsung	6,169.6	9.8%	38.0%	37.0%
Toshiba	2,779.7	1.4%	17.1%	18.0%
WDC	2,616.8	3.7%	16.1%	16.6%
Micron	1,866.0	1.5%	11.5%	12.1%
SK Hynix	1,797.5	19.5%	11.1%	9.9%
Intel	889.0	-0.2%	5.5%	5.9%
Others	116.1	30.9%	0.7%	0.6%
Total	16,234.6	6.8%	--	--

Note 1. 4Q17 USD/JPY= 1:112.9; USD/KRW=1:1,105.0

Note 2. 3Q17 USD/JPY= 1:111.0; USD/KRW=1:1,131.2

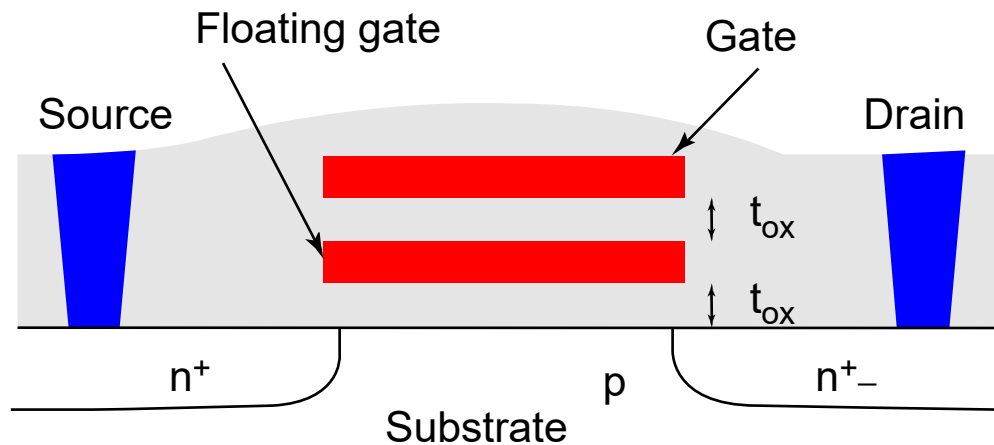
Note 3. Non-captive, license and royalty are excluded from Western Digital's revenue calculation.

Source: DRAMeXchange, Feb., 2018

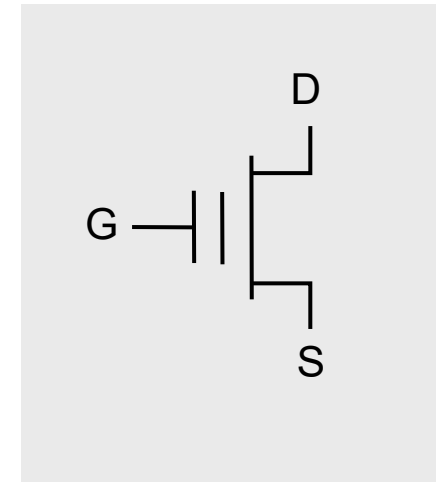
FLASH MEMORY

Non-Volatile Memories

The Floating-gate transistor (FAMOS)

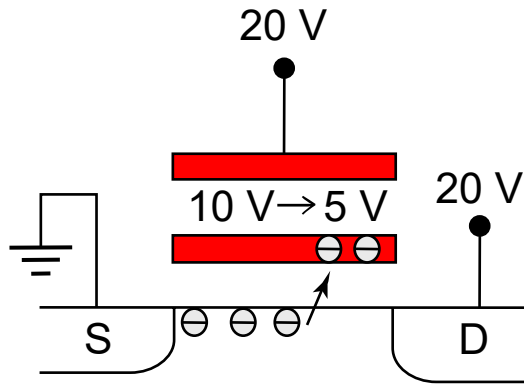


Device cross-section

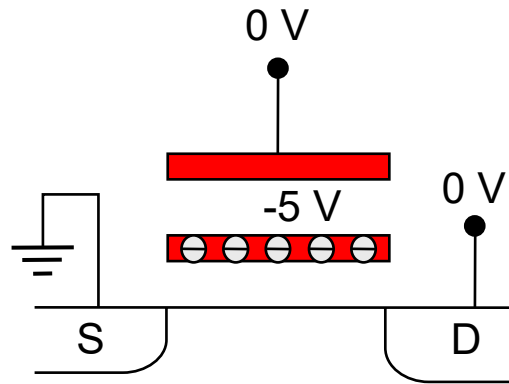


Schematic symbol

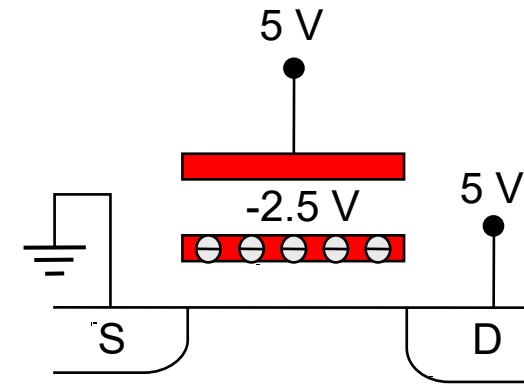
Floating-Gate Transistor Programming



Avalanche injection
Channel Hot Electron
(CHE)

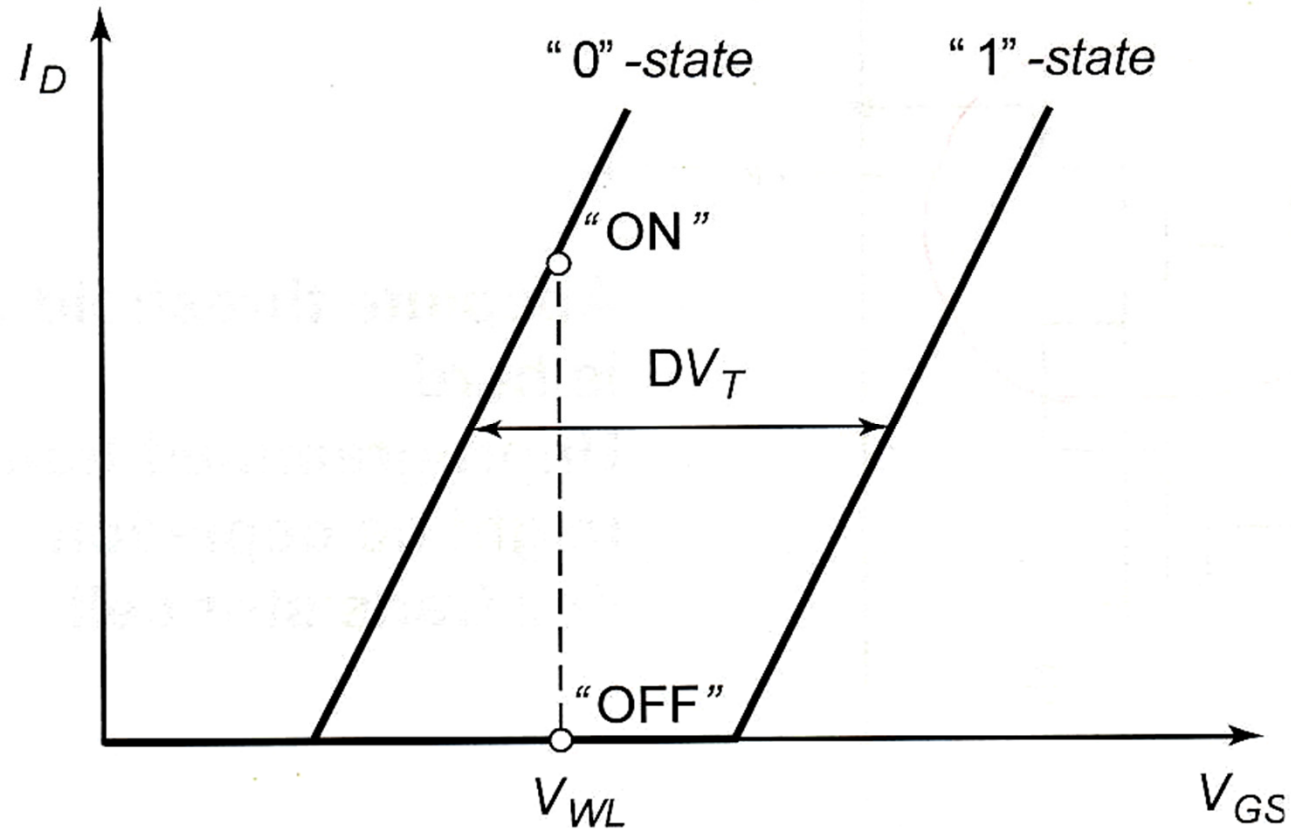


Removing programming
voltage leaves charge trapped

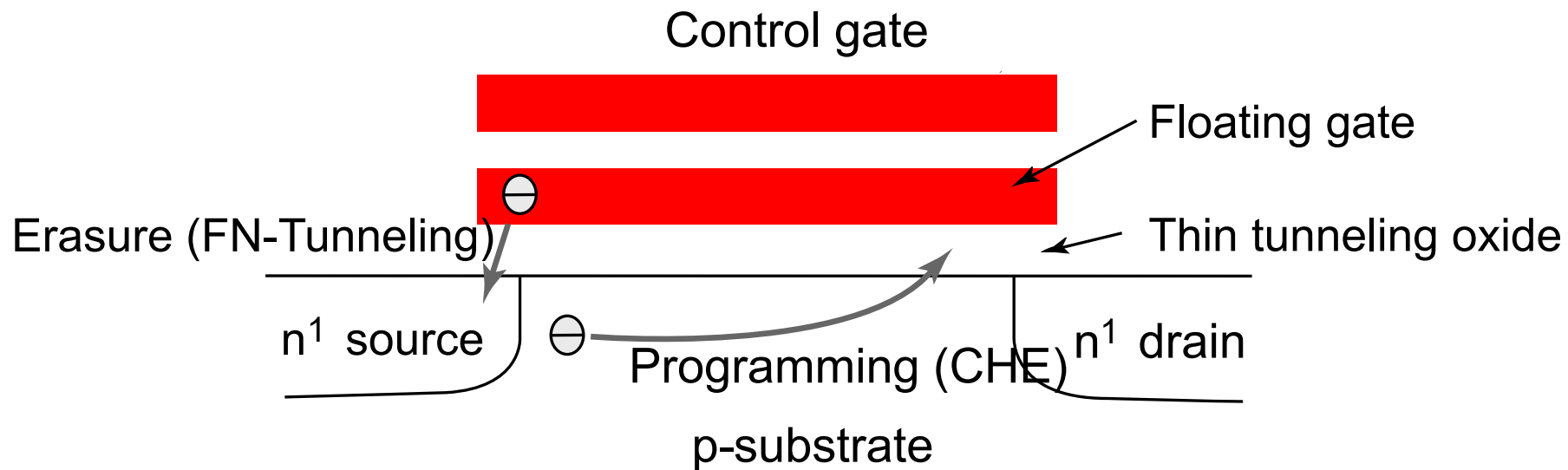


Programming results in
higher V_T .

A “Programmable-Threshold” Transistor



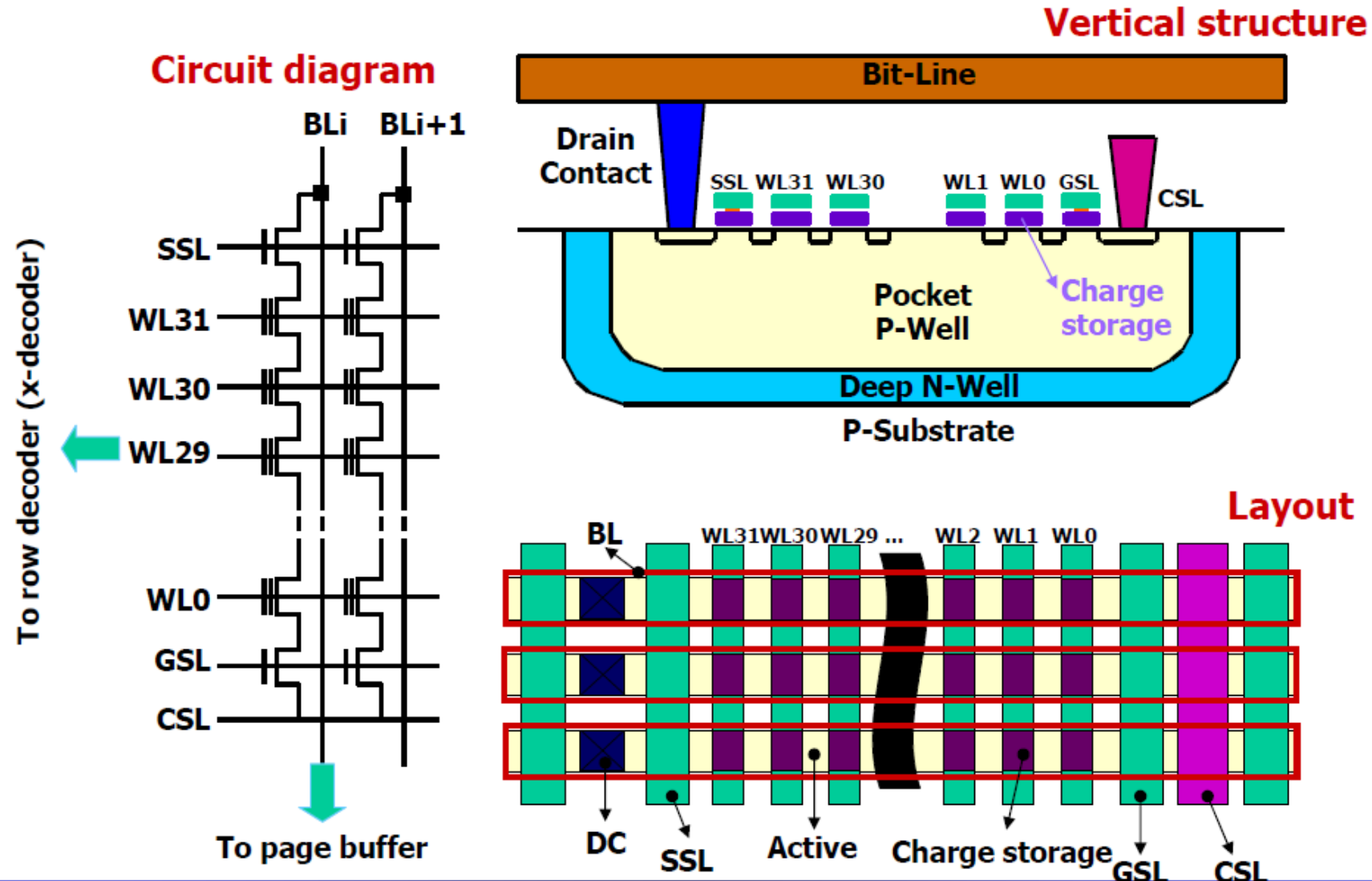
Flash EEPROM



Classical case of Channel Hot Electrons (CHE) and FN-Tunneling
Many other options ...

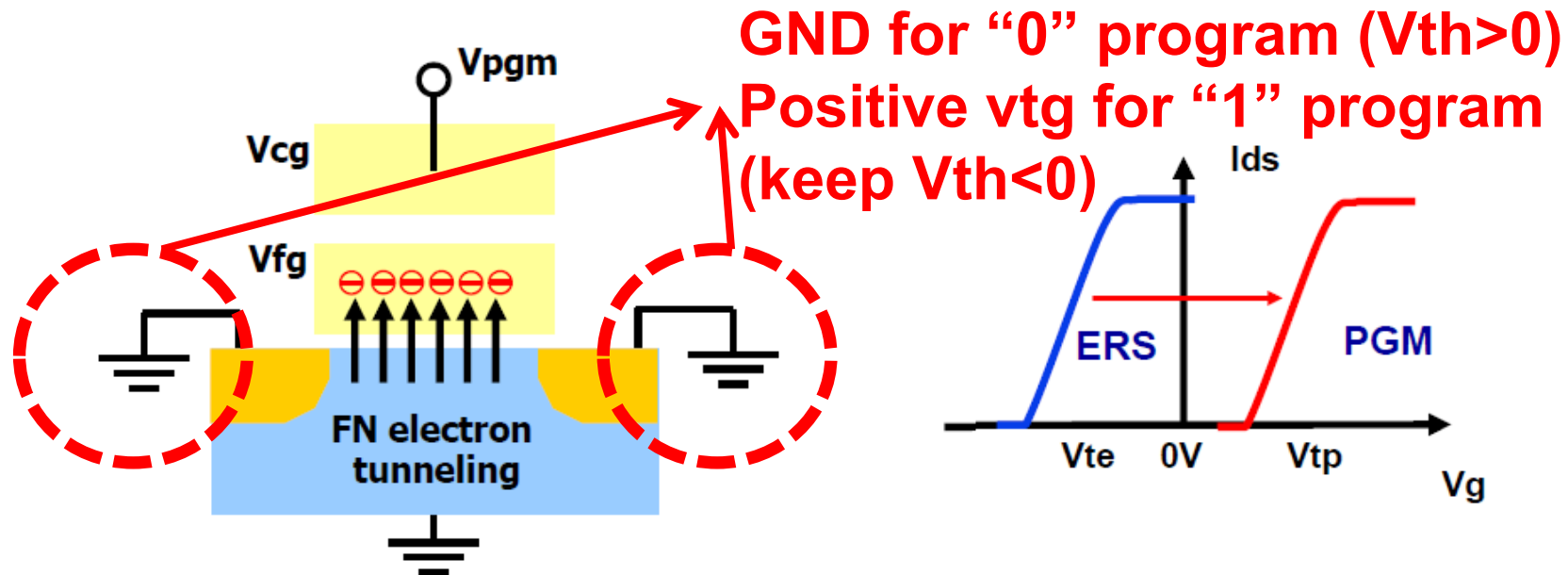
Q) How do we store a new data into a pre-programmed Floating-Gate Transistor?

NAND Flash Memory



NAND Flash: Write Operation

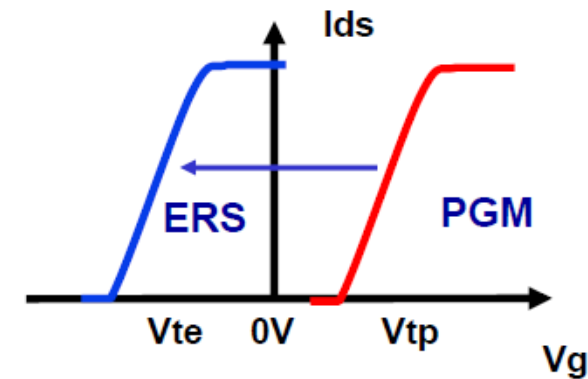
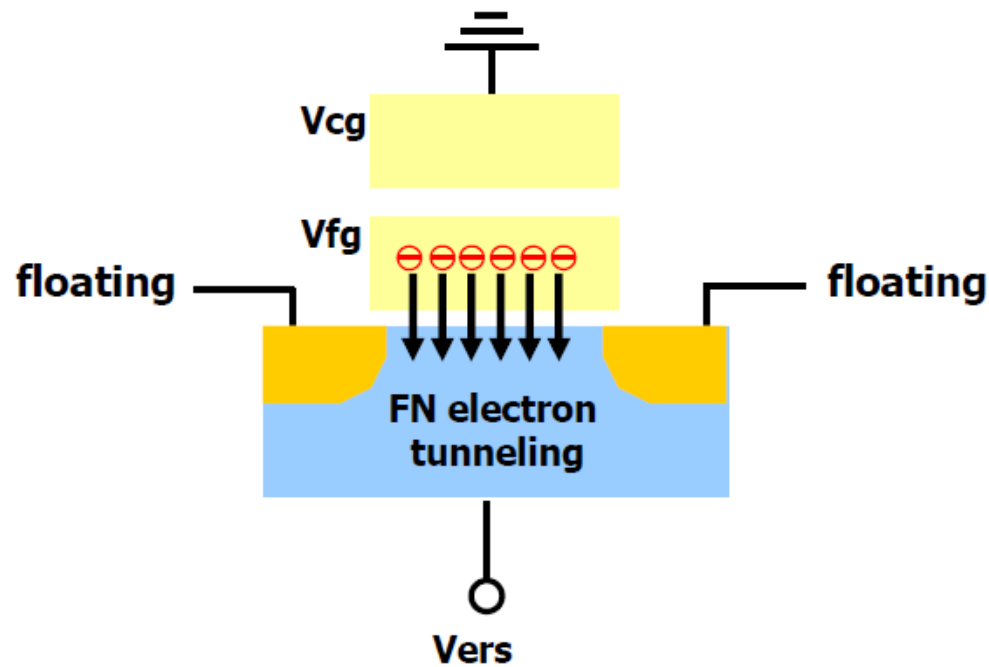
- Inject electrons to the floating gate → Programs V_{th}



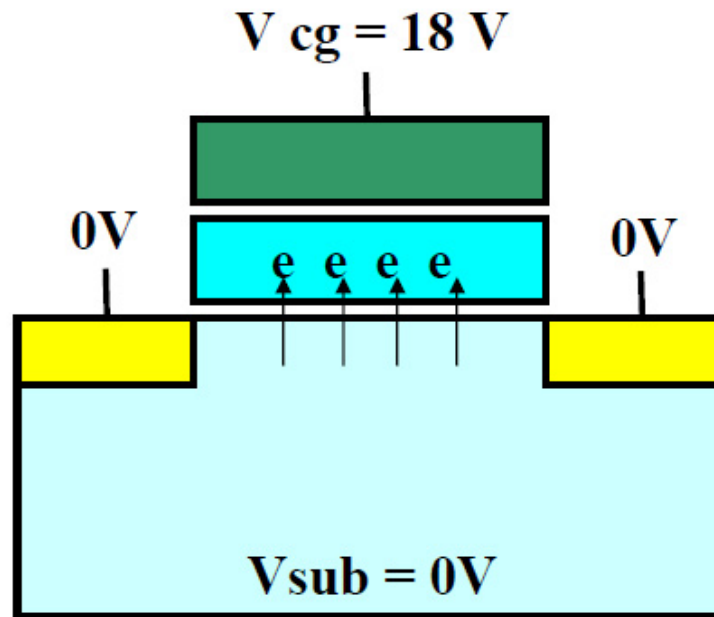
(Note) All cells within a "page" is programmed simultaneously!

NAND Flash: Erase Operation

- Remove electrons from the floating gate
→ Lowers V_{th}

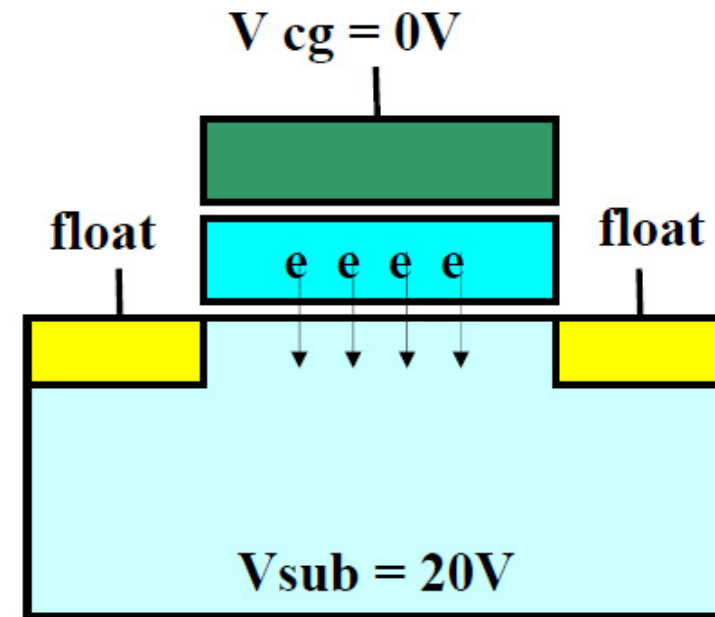


Summary: NAND Program/Erase



Program
F-N Tunneling

Off cell
(Solid-0)

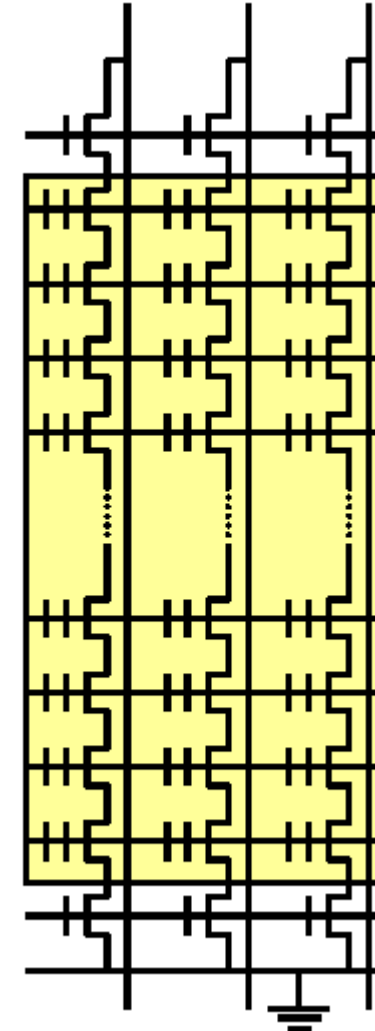
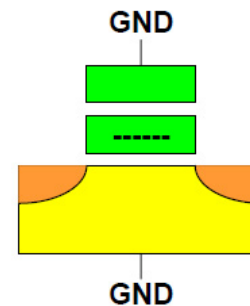
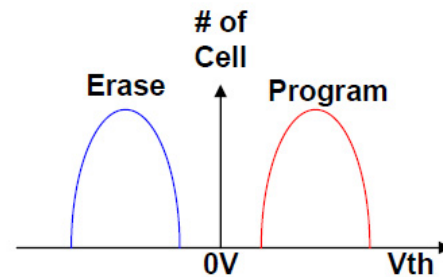
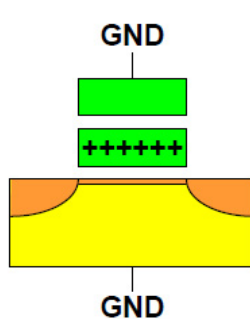


Erase
F-N Tunneling

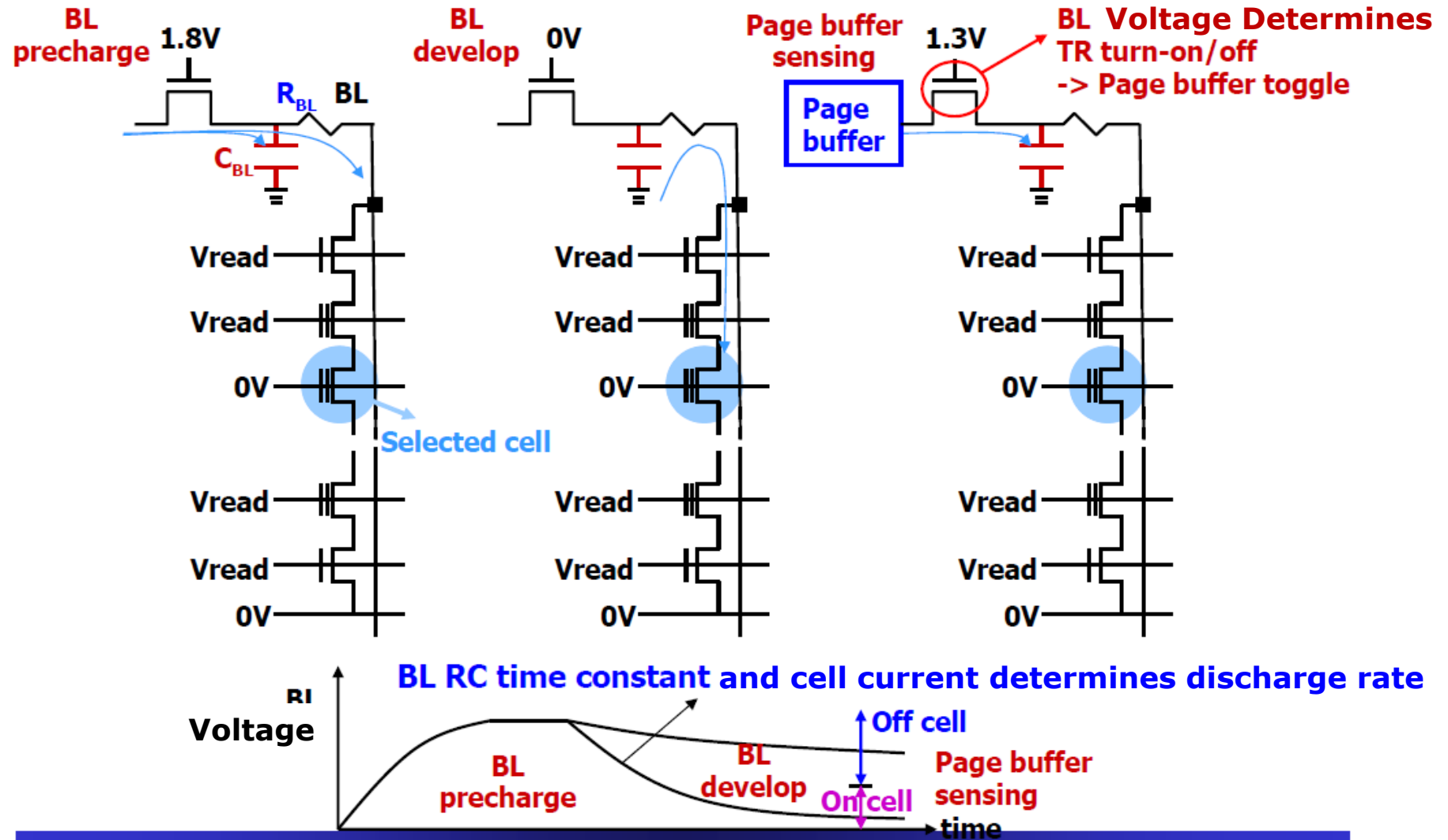
On cell
(Solid-1)

Note: NAND Erase

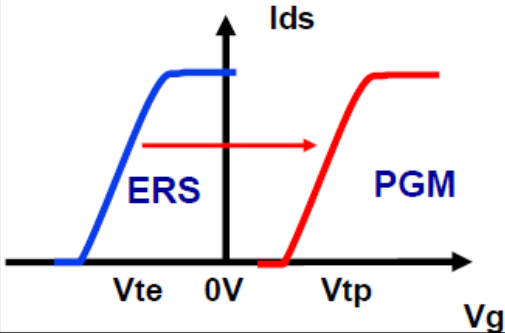
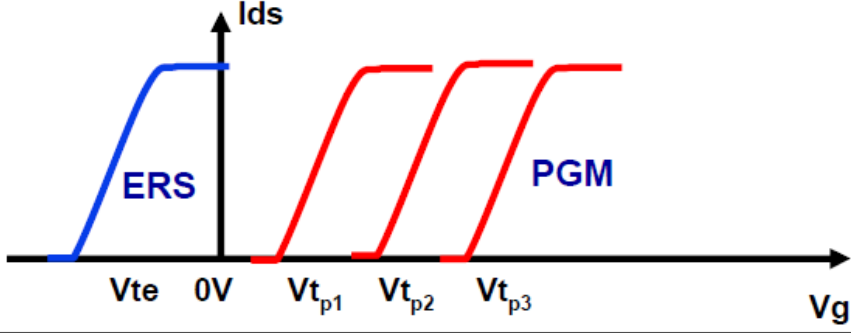
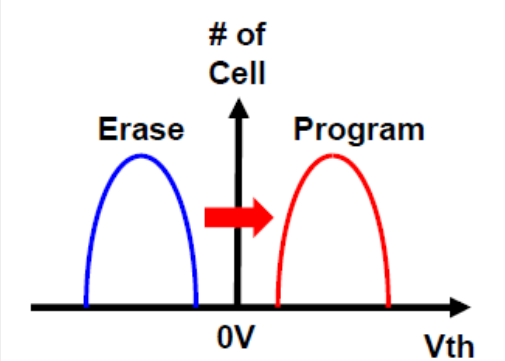
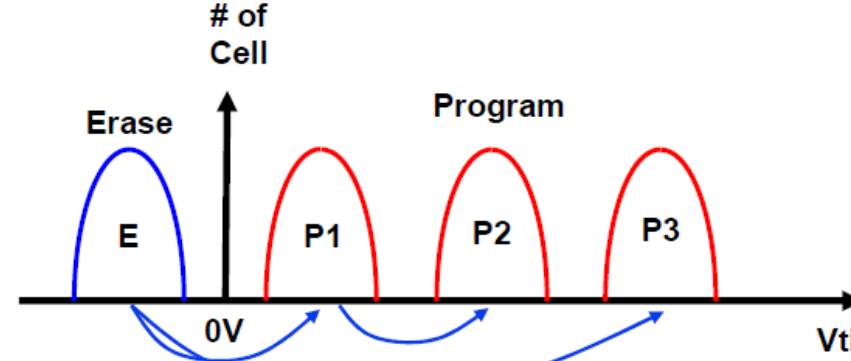
- Erase by “Block” (e.g., 1Mb)
 - Reverse biased body (high V)
 - All WL set to 0V
- Program: $V_{th} > 0$
- Erase: $V_{th} < 0$



NAND Read Sequence



SLC vs. MLC

	SLC (Single Level Cell)	MLC (Multi Level Cell)
Vg-Id	 <p>The graph shows the drain current I_{ds} versus gate voltage V_g. A blue curve labeled 'ERS' starts at V_{te} and rises to a plateau. A red curve labeled 'PGM' starts at V_{tp} and rises to a higher plateau. A red arrow points from the ERS curve to the PGM curve, indicating a shift in the threshold voltage.</p>	 <p>The graph shows the drain current I_{ds} versus gate voltage V_g. A blue curve labeled 'ERS' starts at V_{te} and rises to a plateau. Three red curves labeled 'PGM' start at V_{tp1}, V_{tp2}, and V_{tp3} and rise to higher plateaus. This shows multiple distinct threshold voltage levels for programming.</p>
Vth Dist	 <p>The graph shows the number of cells versus threshold voltage V_{th}. A blue curve labeled 'Erase' is centered around 0V. A red curve labeled 'Program' is centered at a higher V_{th} value. A red arrow points from the Erase curve to the Program curve.</p>	 <p>The graph shows the number of cells versus threshold voltage V_{th}. A blue curve labeled 'E' is centered around 0V. Three red curves labeled 'P1', 'P2', and 'P3' are centered at progressively higher V_{th} values. Blue arrows indicate the distribution of cells across these multiple levels.</p>
Note	1 bit per cell	Multiple bits per cell

SRAM / DRAM

Read-Write Memories (RAM)

❑ STATIC (SRAM)

Data stored as long as supply is applied

Large (6 transistors/cell)

Fast

Differential

❑ DYNAMIC (DRAM)

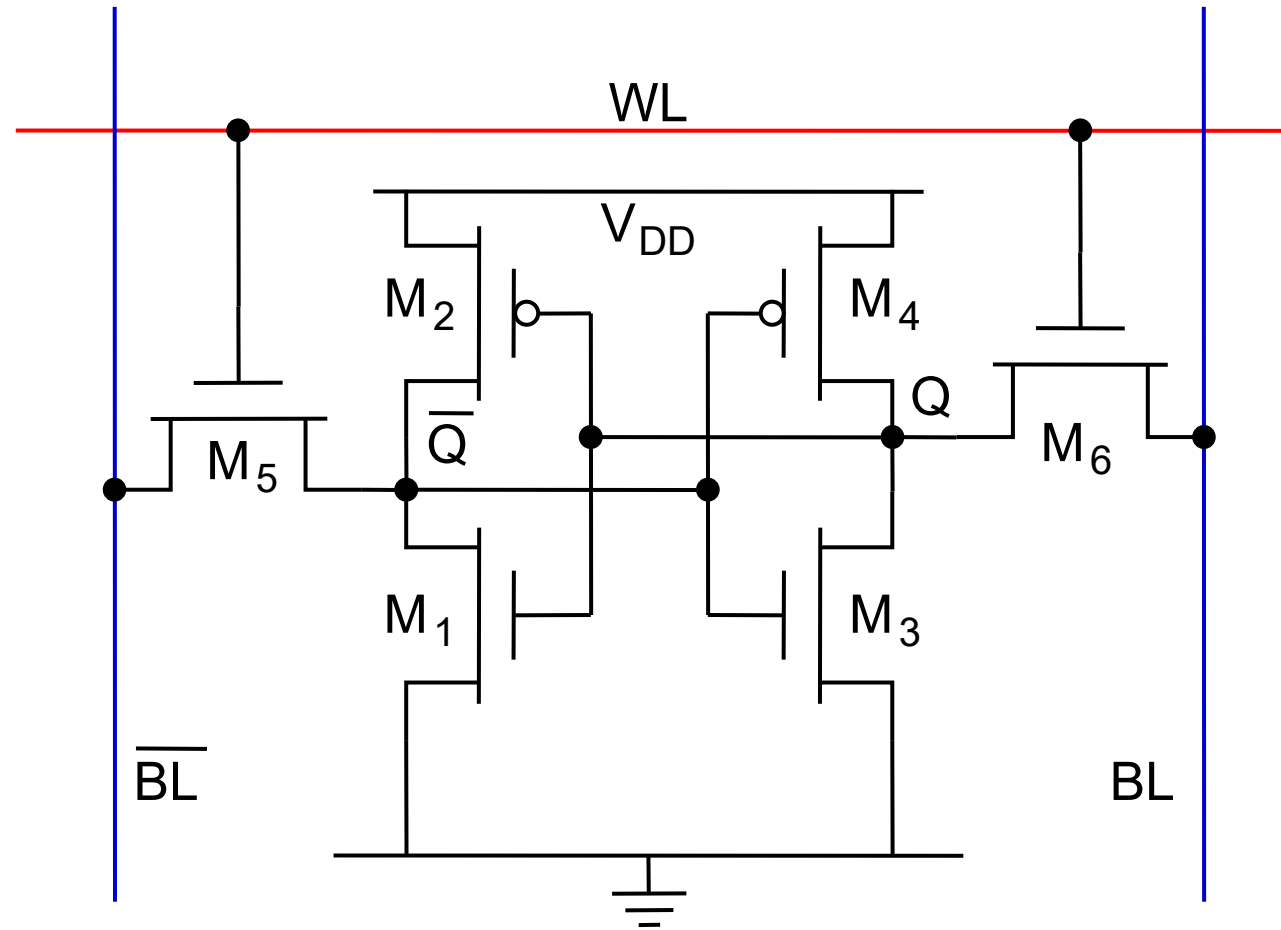
Periodic refresh required

Small (1-3 transistors/cell)

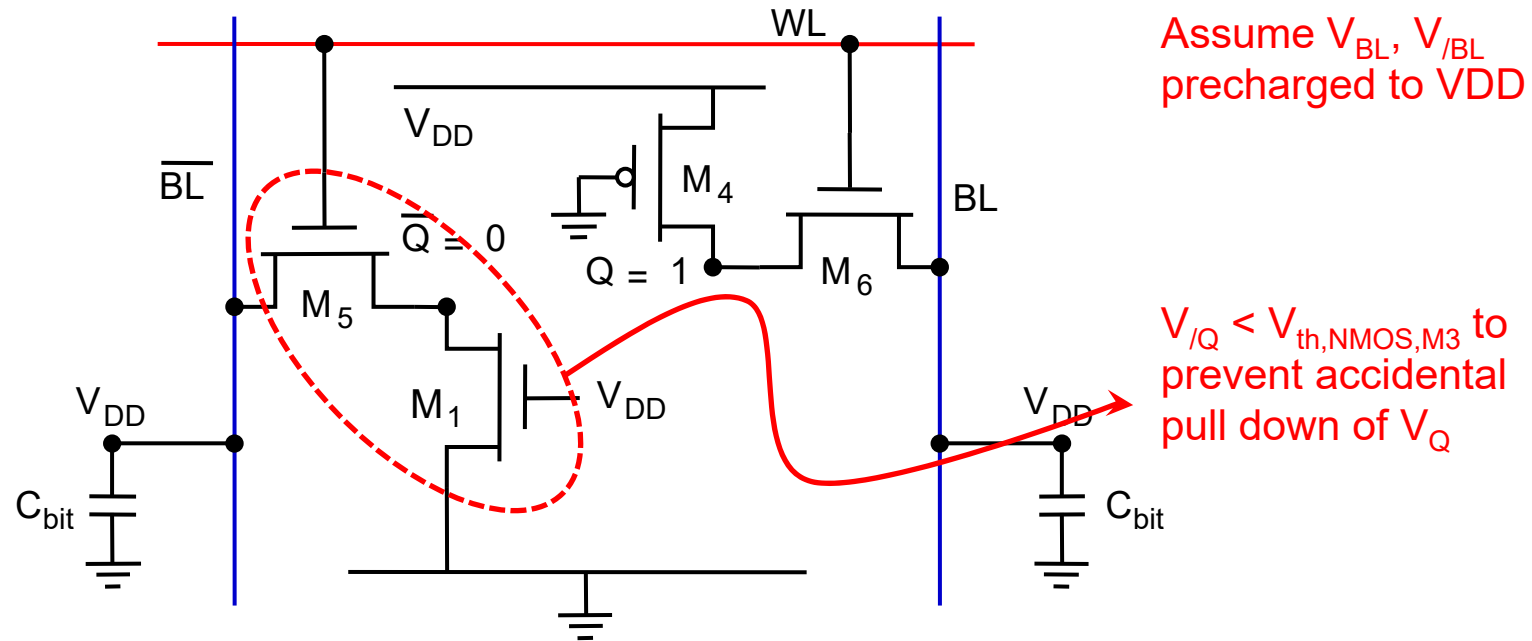
Slower

Single Ended

6-transistor CMOS SRAM Cell



CMOS SRAM Analysis (Read)

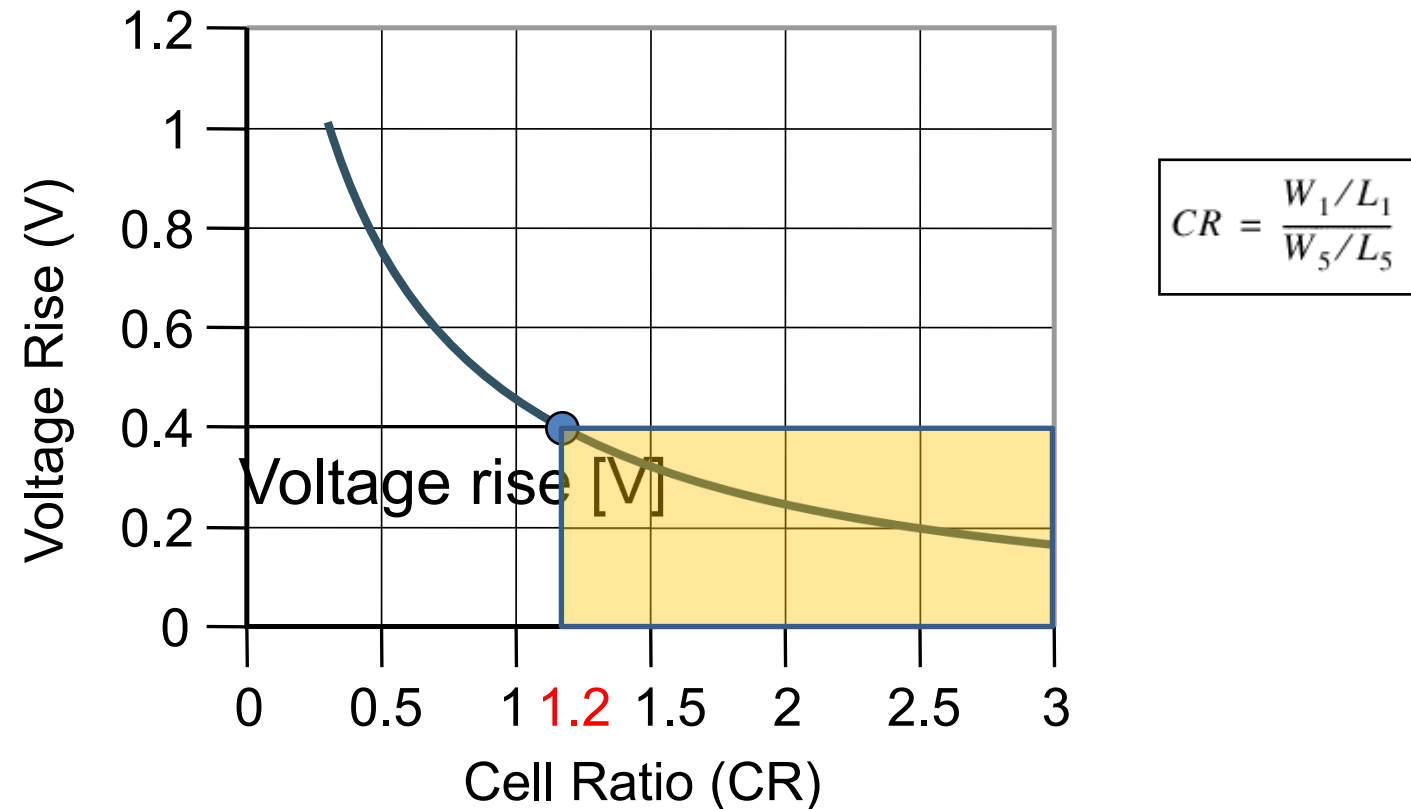


$$k_{n,M5} \left((V_{DD} - \Delta V - V_{Tn}) V_{DSATn} - \frac{V_{DSATn}^2}{2} \right) = k_{n,M1} \left((V_{DD} - V_{Tn}) \Delta V - \frac{\Delta V^2}{2} \right)$$

$$\Delta V = \frac{V_{DSATn} + CR(V_{DD} - V_{Tn}) - \sqrt{V_{DSATn}^2(1 + CR) + CR^2(V_{DD} - V_{Tn})^2}}{CR}$$

$$CR = \frac{W_1/L_1}{W_5/L_5}$$

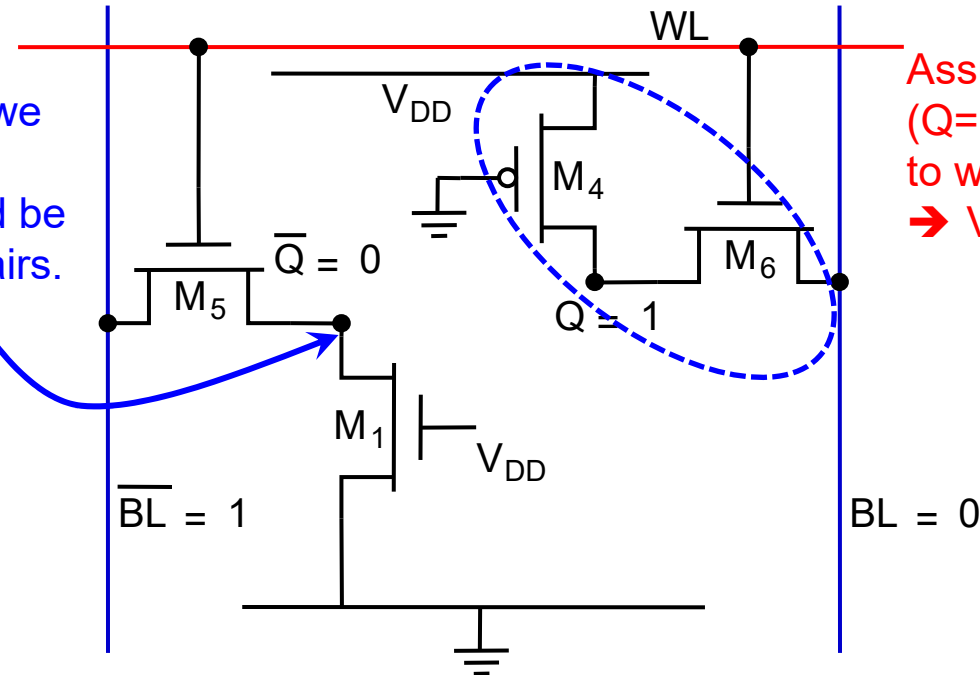
CMOS SRAM Analysis (Read)



CR > 1.2 to ensure read stability
(otherwise, bit flip occurs while read operation)

CMOS SRAM Analysis (Write)

From read analysis, we know $V_{IQ} < 0.4(V)$
 → Write of "0" should be initiated by M4/M6 pairs.



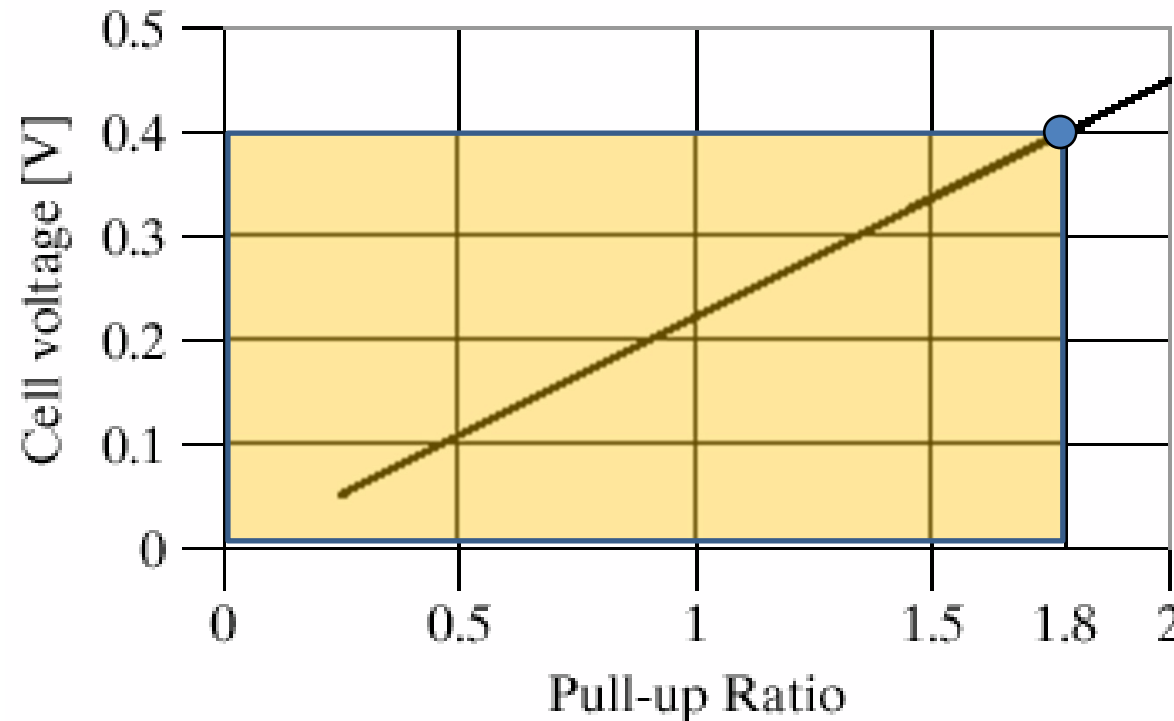
Assume 1 is stored ($Q=1$) and we want to write "0".
 → $V_{BL}=0$, $V_{BL-bar}=1$

$$k_{n,M6} \left((V_{DD} - V_{Tn}) V_Q - \frac{V_Q^2}{2} \right) = k_{p,M4} \left((V_{DD} - |V_{Tp}|) V_{DSATp} - \frac{V_{DSATp}^2}{2} \right)$$

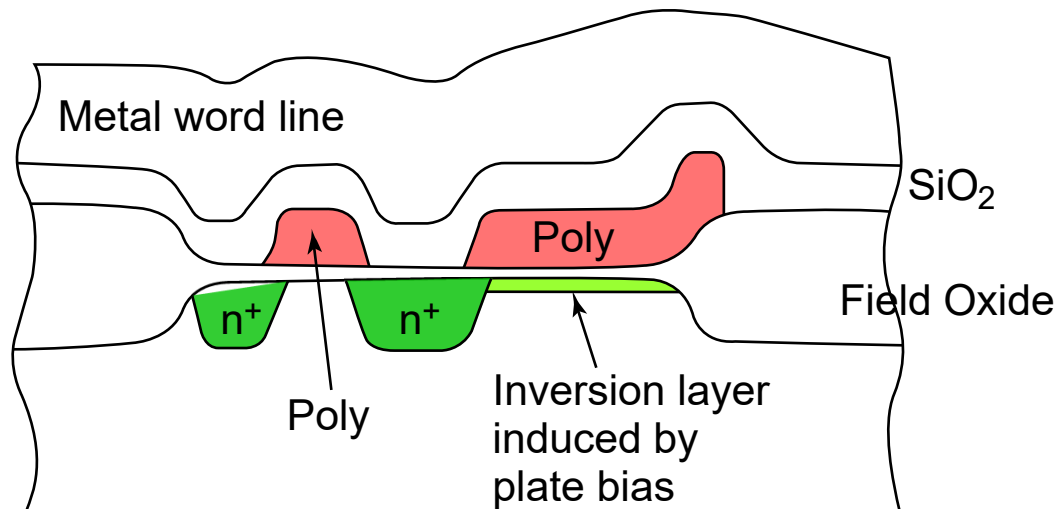
$$V_Q = V_{DD} - V_{Tn} - \sqrt{(V_{DD} - V_{Tn})^2 - 2 \frac{\mu_p}{\mu_n} PR \left((V_{DD} - |V_{Tp}|) V_{DSATp} - \frac{V_{DSATp}^2}{2} \right)}, \quad PR = \frac{W_4/L}{W_1/L}$$

→ V_Q should be lower than $V_{th,M1}$
 (otherwise, M1 is kept on, and 0 cannot be written to Q)

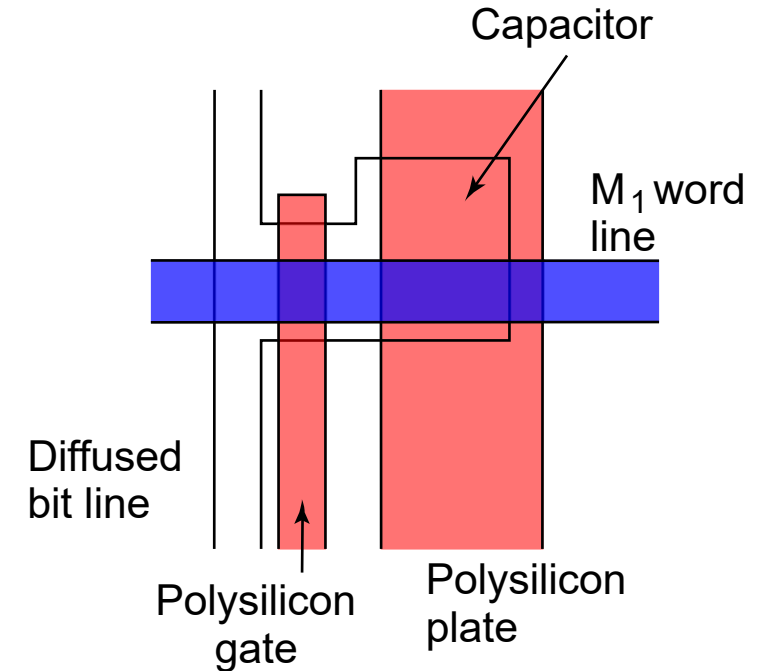
CMOS SRAM Analysis (Write)



PR < 1.8 to ensure write of "0"
(otherwise, M1 stays on and we cannot write "0" into Q)



Cross-section

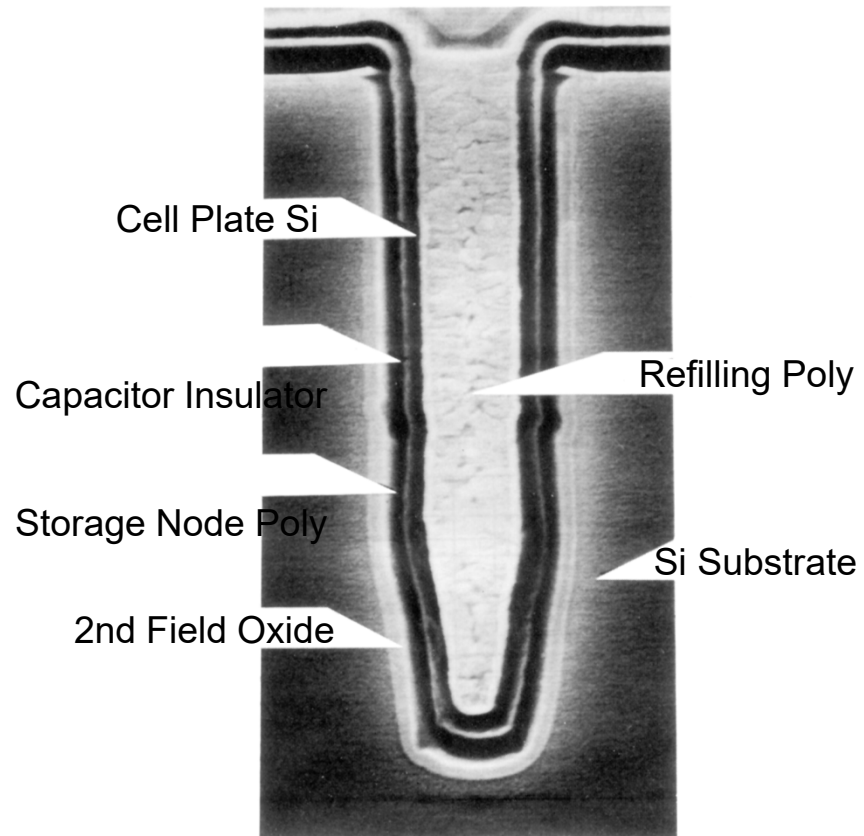


Layout

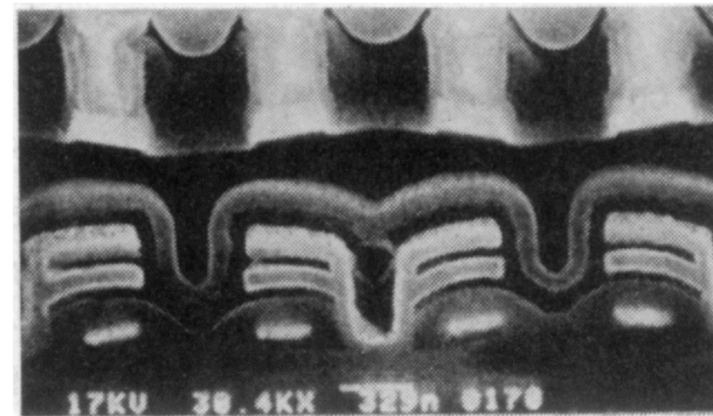
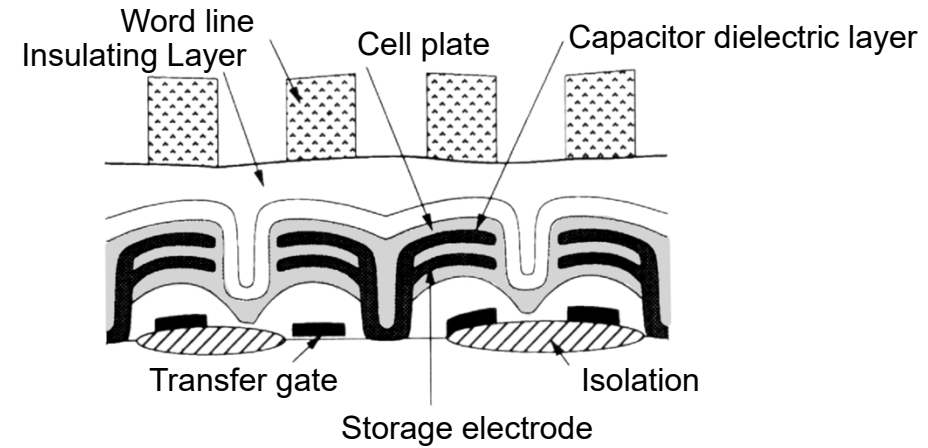
Uses Polysilicon-Diffusion Capacitance

Expensive in Area

Advanced 1T DRAM Cells

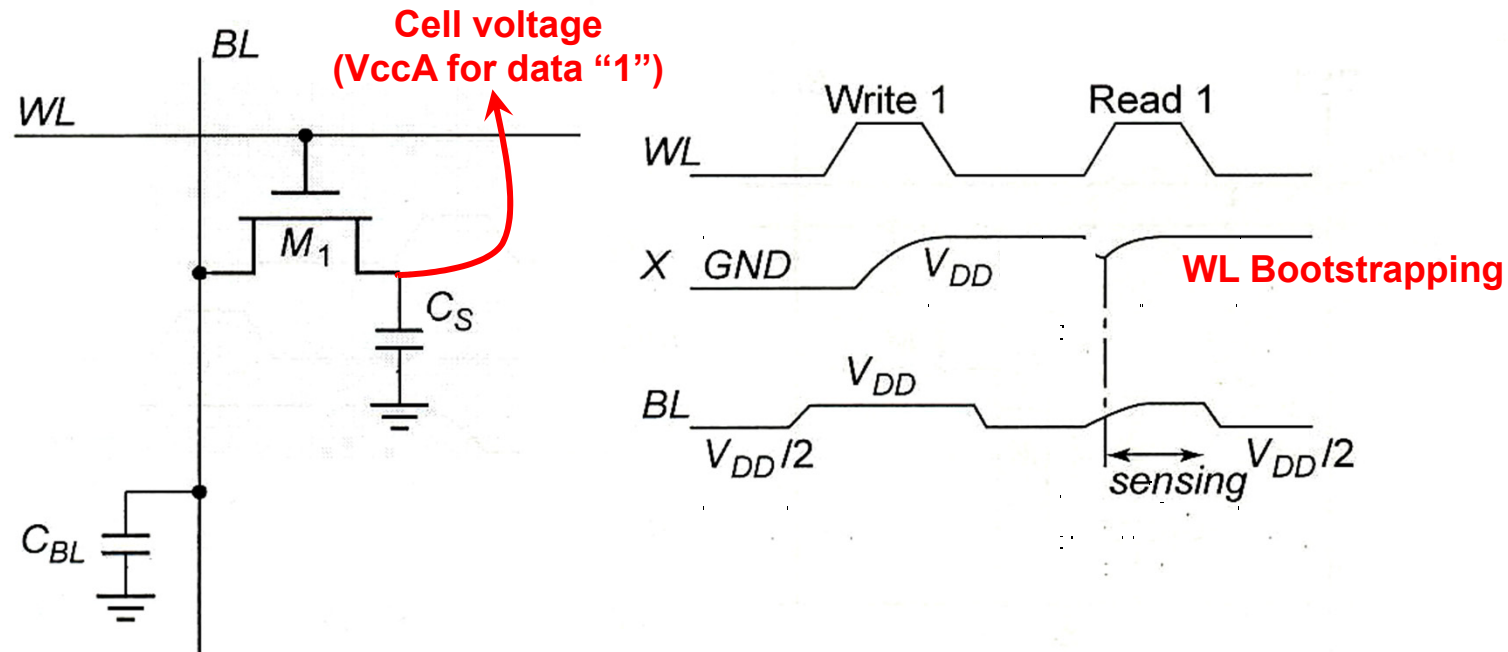


Trench Cell



Stacked-capacitor Cell

1-Transistor DRAM Cell

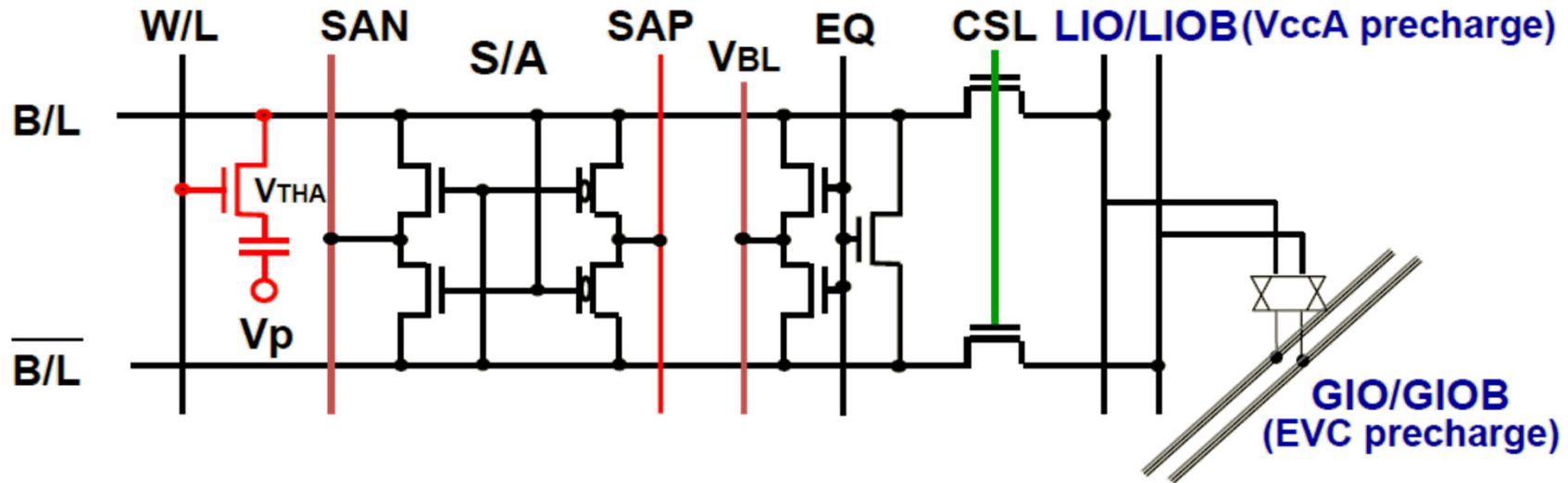


If VCs was initially charged up to V_{ccA} (data "1"),

$$V_{\text{Final}} (C_{BL} + C_S) = C_{BL} V_{ccA}/2 + C_S V_{ccA}$$

$$\rightarrow \Delta V = V_{\text{Final}} - 1/2 V_{ccA} = \frac{V_{ccA}/2}{1 + C_{BL}/C_S}$$

DRAM Capacitance Ratio



Parasitic Capacitance Example

	Capacitance	Ratio
Cell, C_s	25 fF	1
Bit Line, C_b	100 fF	4
LIO Line	200 fF	8
GIO Line	1.5 pF	60

Charge Sharing

Stored Charge : $V_{ccA} \cdot C_s$

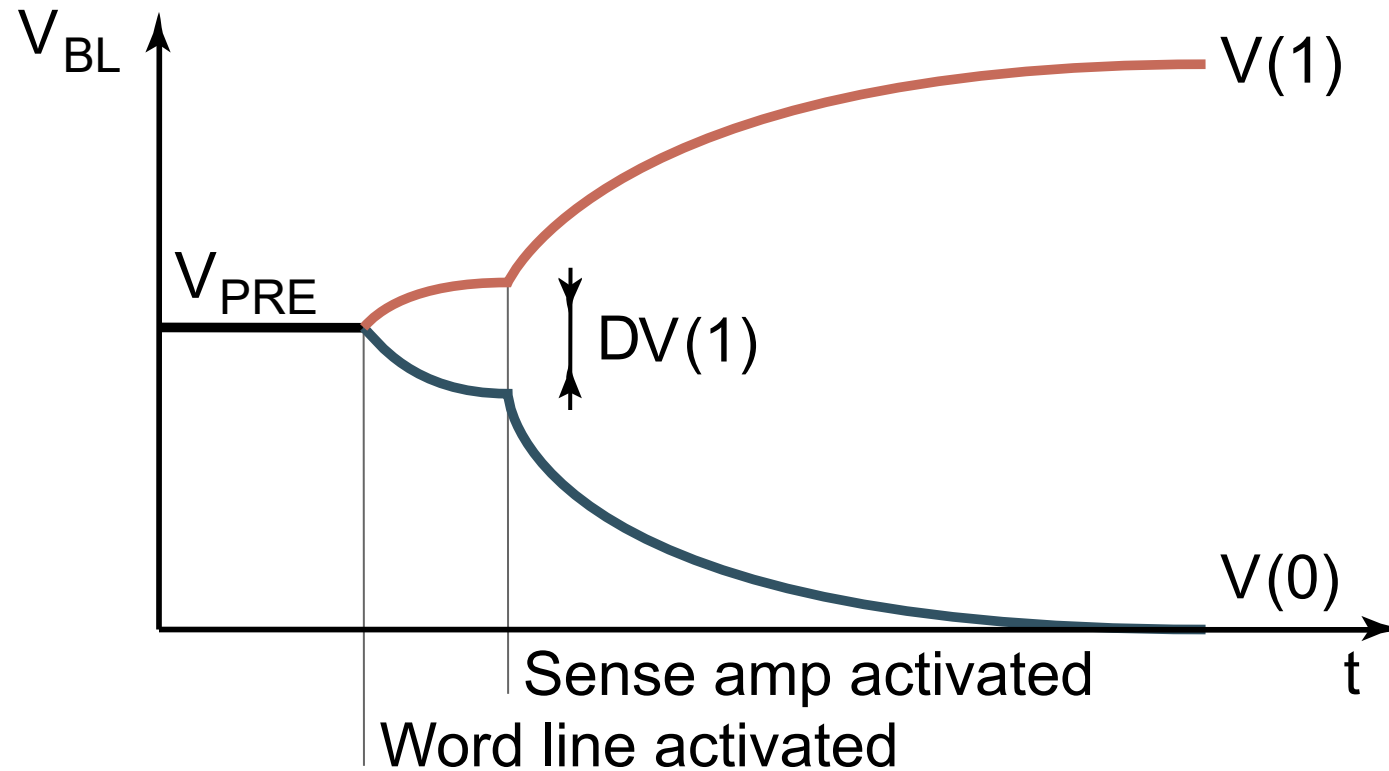
$$\Delta V_{BL} : V_{ccA}/2 \cdot \frac{C_s}{C_b + C_s}$$

Example, $\Delta V_{BL} = 150\text{mV}$
for $V_{ccA} = 1.5\text{V}$

DRAM Cell Observations

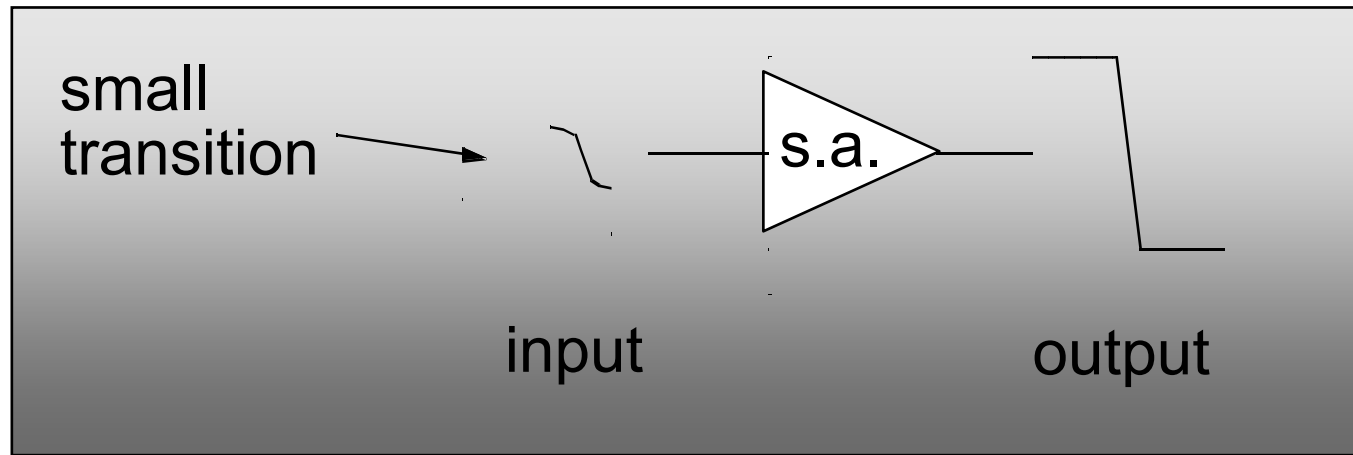
- 1T DRAM requires a sense amplifier for each bit line, due to charge redistribution read-out.
- DRAM memory cells are single ended in contrast to SRAM cells.
- The read-out of the 1T DRAM cell is destructive; read and refresh operations are necessary for correct operation.
- When writing a “1” into a DRAM cell, a threshold voltage is lost. This charge loss can be circumvented by bootstrapping the word lines to a higher value than V_{DD}

Sense Amp Operation

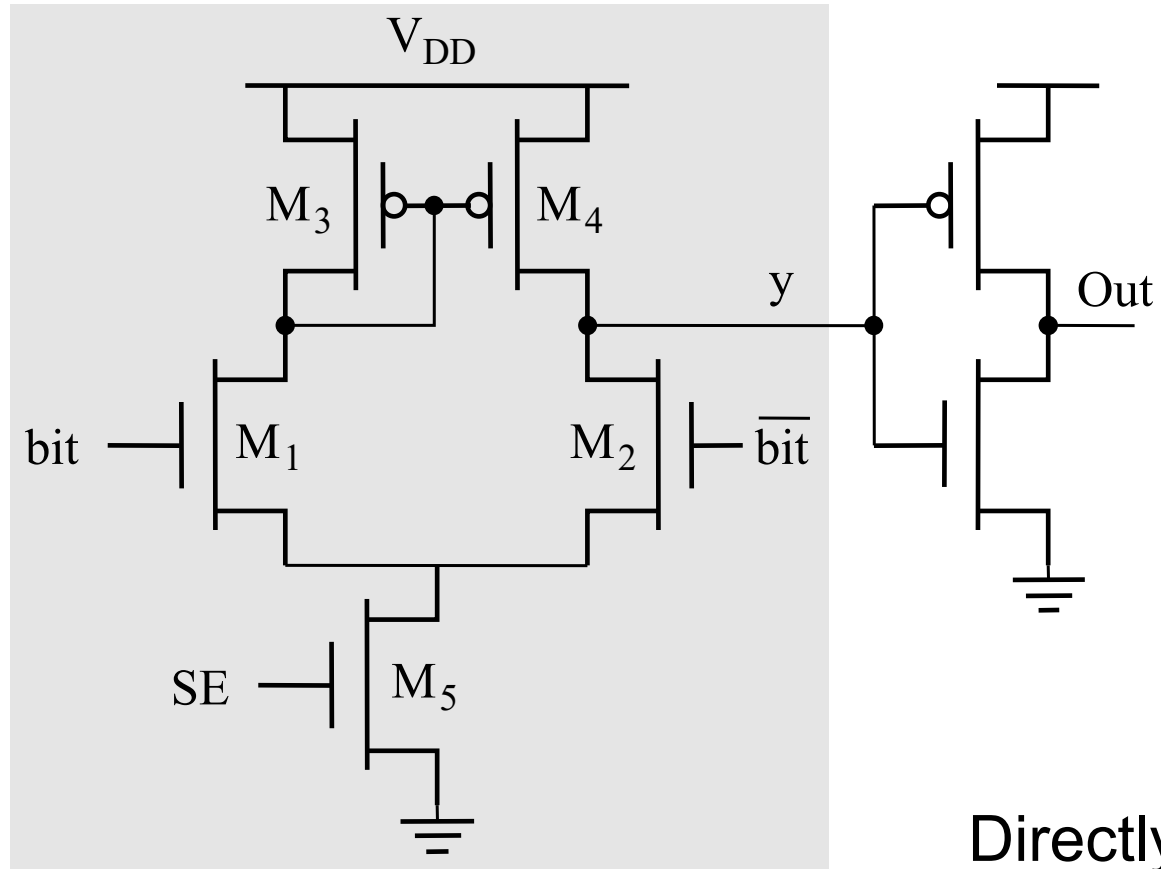


Sense Amplifiers

Idea: Use Sense Amplifier

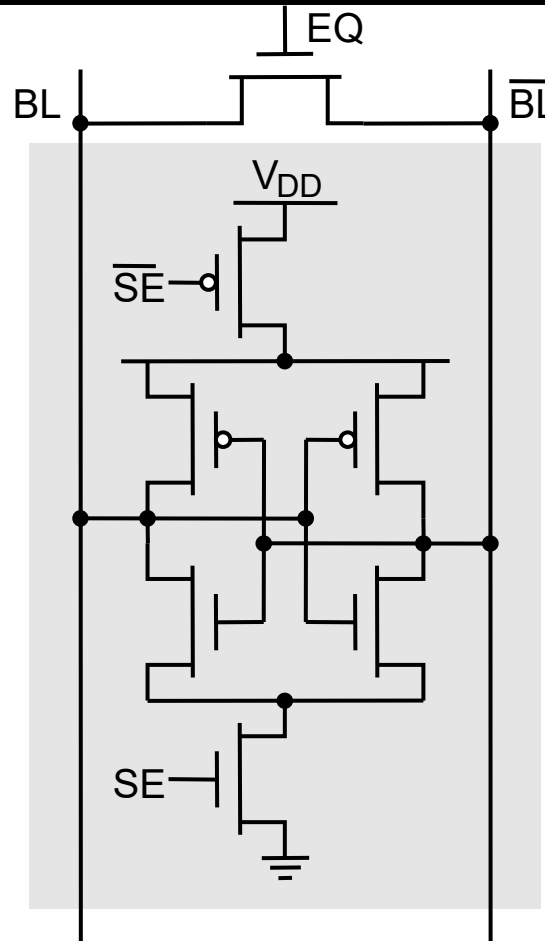


Differential Sense Amplifier



Directly applicable to
SRAMs

Latch-Based Sense Amplifier (DRAM)



Initialized in its meta-stable point with EQ

Once adequate voltage gap created, sense amp enabled with SE
Positive feedback quickly forces output to a stable operating point.

FUTURE MEMORIES

Ideal Memory System

- Supply all (any) data that processor needs
 - Capacity, Cost = small cell/die size, scalability
- In a moment
 - Latency / Bandwidth
- With low power consumption and good reliability
 - Non-volatility

Bandwidth vs. Latency

- **Latency** (=Execution Time, Response Time)
 - The time between the start and the completion of an event.
 - **Bandwidth** (=Throughput)
 - The total amount of work done in a given time
- ➔ The terms “**latency**” and “**bandwidth**” are “the terms of choice” when discussing a high performance memory system

Comparison of Si Memories

	DRAM	SRAM	NAND	NOR	FRAM	PRAM
Cell size	2	6	1	4	5	2
Latency	2	1	6	5	2	4
Data rate	2	1	4	5	2	6
Low Vcc	2	1	6	5	2	3
Non-volatility	6	6	1	1	1	1
Endurance	1	1	6	6	2	3
Tech. migration	1	6	1	4	6	1
High Density	2	6	1	3	6	2
Market size	1	4	2	3	5	N.A

1 ← Best Worst → 6

Chalcogenide Material

- The general class of switching media in CD-RW and DVD-RW
 - In high volume production and low cost
- Laser beam energy is used to control the switching between crystalline and amorphous phases
 - Higher energy → amorphous
 - Medium energy → crystalline
- Low energy laser beam to read

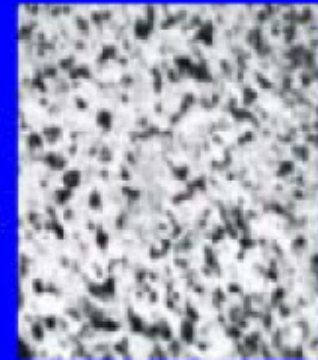
Phase-Change RAM (PRAM)

Amorphous vs Crystalline Phases

Amorphous
Phase



Scale:
0.2 microns



Crystalline
Phase

Electron Diffraction Patterns

Short Range Atomic Order
Low Free Electron Density
High Activation Energy
High Resistivity



Long Range Atomic Order
High Free Electron Density
Low Activation Energy
Low Resistivity

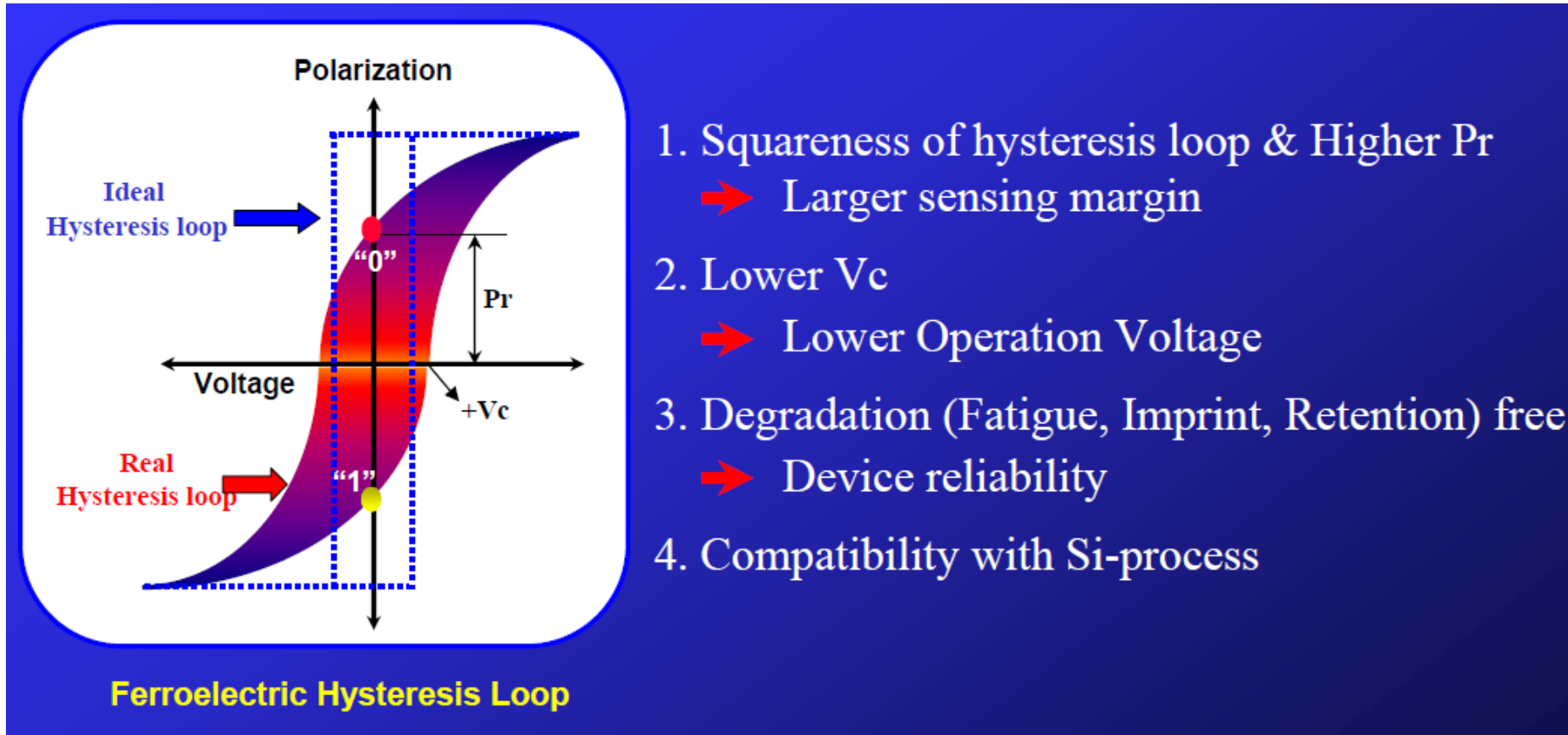


Material Characteristics

PRAM Properties

- **Strong points and General properties**
 - Signal Sensing Margin : $R_{\text{reset}} / R_{\text{set}} \sim 10^3$
 - Programming Speed : $\leq 300 \text{ nsec}$
 - Endurance : $> 10^9$ (Read), $10^7 \sim 10^9$ (Write)
 - Retention Characteristics : 10 years @110°C ~ 130°C
- **Technical Challenges**
 - Programming Current : 0.6 mA ~ 1mA
 - Set Resistance : 1kΩ ~ 10kΩ
 - Degradation due to Integration : Heat, Contamination

Ferroelectric RAM (FRAM)

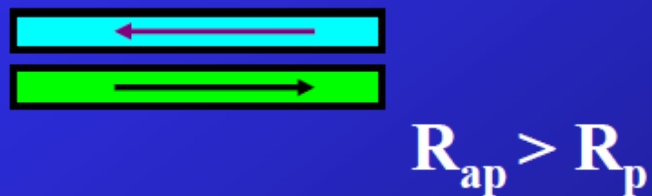
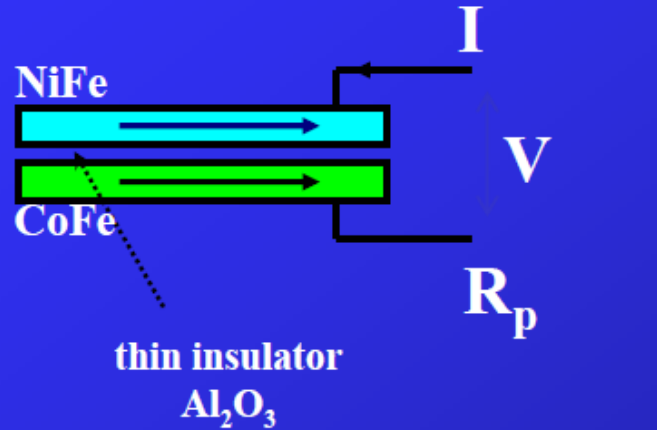


FRAM Properties

- **Strong points and General properties**
 - Programming Speed : ≤ 100 nsec
 - Endurance : $> 10^{11}$ (Write / Read)
 - Retention Characteristics : > 10 years @85°C
- **Technical Challenges**
 - Thin Ferroelectric Film : ~ 70 nm
 - Low Voltage Operation : ≤ 1.2 V
 - High Etching Slope : $\sim 82^\circ$
 - Degradation Free Integration
 - 3-Dim. Conformal Deposition : Not Yet

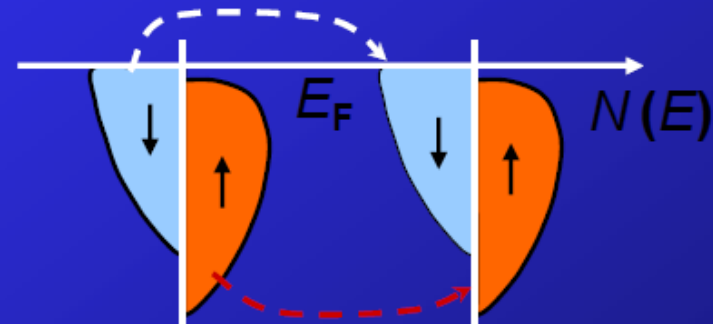
Magnetic RAM (MRAM)

Magnetic tunnel junction

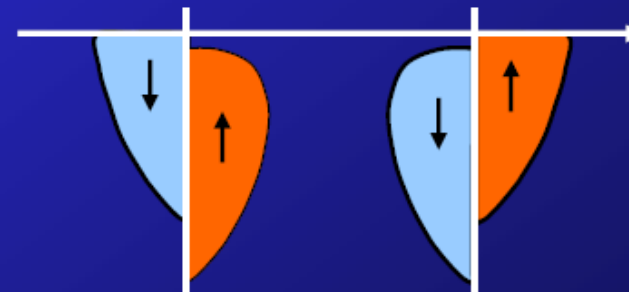


$$MR = \frac{R_{ap} - R_p}{R_p}$$

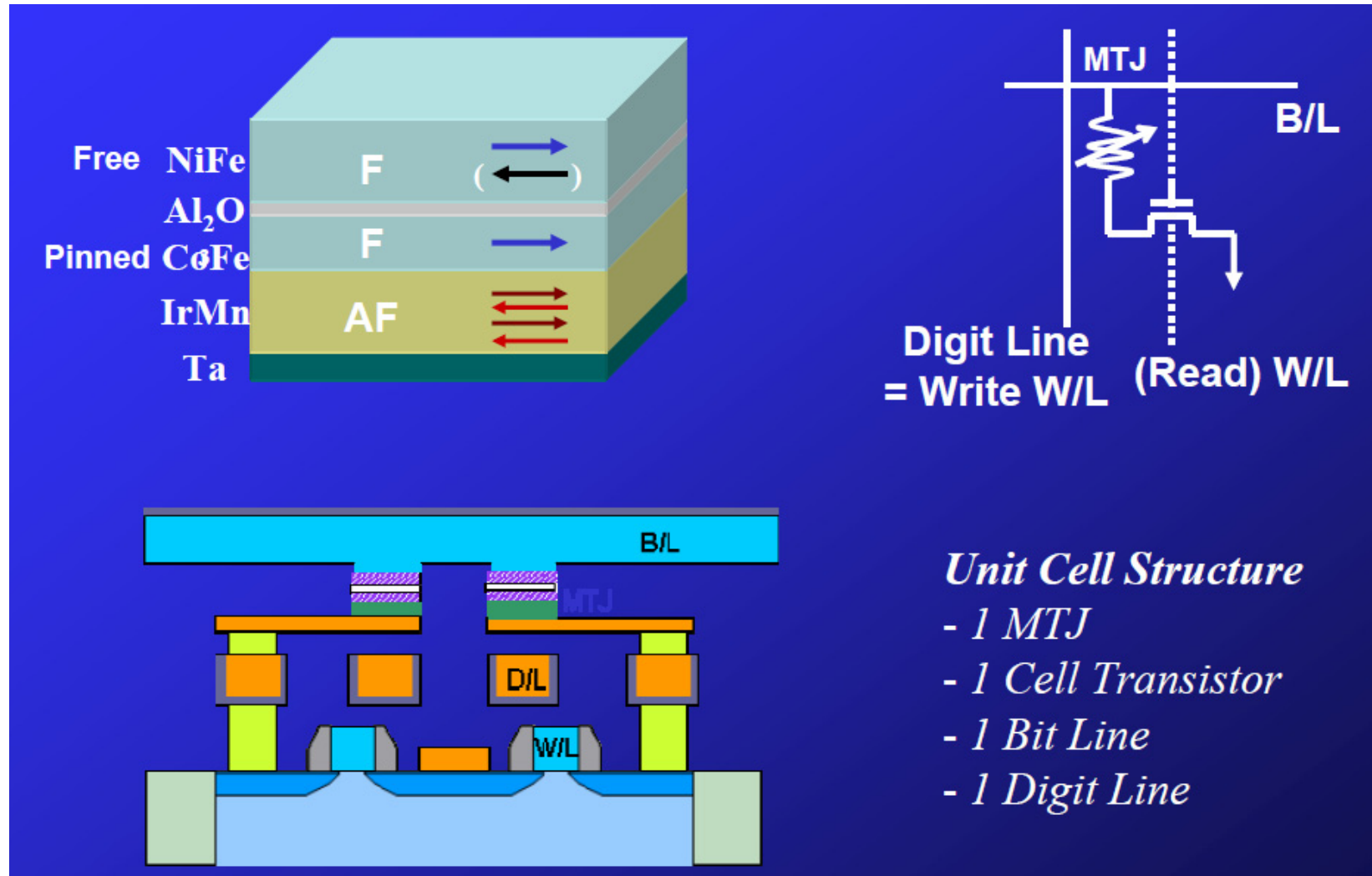
(1) Parallel magnetization → Low R



(2) Anti-parallel magnetization → High R



MRAM cell structure



Comparison of NVM

Parameter	NAND Flash	NOR Flash	FRAM	MRAM	PRAM
Random access	no	yes	yes	yes	yes
Cell Size (Achieved)	4F ²	10F ²	15F ²	>40F ²	~10F ² (Bi) ~30F ² (MOS)
Cell Size (Achievable)	4F ²	10F ²	15F ²	30F ²	6F ²
Scalability	Good	Good	Bad	Worse	Good
Limit	Coupling	Drain Disturb.	Capacitor	Writing Current	Reset Current
Write cycles	10 ⁵	10 ⁵	>10 ¹²	>10 ¹²	>10 ¹²
Write Speed (Pgm.) (Erase)	200us/Page 1ms/Block	10us/Byte 1s/Sect.(64kB)	< 100ns N.A.	<100ns N.A.	~100ns N.A.

- PRAM (density)
- MRAM & FRAM (nearly ideal except for density)